Alessandra Leonhardt

List of Publications by Year in descending order

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933447 1125743 14 275 10 13 citations g-index h-index papers 14 14 14 522 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Layer-controlled epitaxy of 2D semiconductors: bridging nanoscale phenomena to wafer-scale uniformity. Nanotechnology, 2018, 29, 425602.	2.6	48
2	Material-Selective Doping of 2D TMDC through Al <i>_x</i> <col/> _yEncapsulation. ACS Applied Materials & Samp; Interfaces, 2019, 11, 42697-42707.	8.0	37
3	Improving MOCVD MoS ₂ Electrical Performance: Impact of Minimized Water and Air Exposure Conditions. IEEE Electron Device Letters, 2017, 38, 1606-1609.	3.9	33
4	Multicomponent Covalent Chemical Patterning of Graphene. ACS Nano, 2021, 15, 10618-10627.	14.6	31
5	Devices and Circuits Using Novel 2-D Materials: A Perspective for Future VLSI Systems. IEEE Transactions on Very Large Scale Integration (VLSI) Systems, 2019, 27, 1486-1503.	3.1	30
6	Growth of Millimeter-Sized Graphene Single Crystals on Al ₂ O ₃ (0001)/Pt(111) Template Wafers Using Chemical Vapor Deposition. ECS Journal of Solid State Science and Technology, 2018, 7, M195-M200.	1.8	20
7	Graphene based Van der Waals contacts on MoS ₂ field effect transistors. 2D Materials, 2021, 8, 015003.	4.4	15
8	The Role of Nonidealities in the Scaling of MoS ₂ FETs. IEEE Transactions on Electron Devices, 2018, 65, 4635-4640.	3.0	14
9	Understanding ambipolar transport in MoS ₂ field effect transistors: the substrate is the key. Nanotechnology, 2021, 32, 135202.	2.6	14
10	(Invited) Internal Photoemission of Electrons from 2-Dimensional Semiconductors. ECS Transactions, 2017, 80, 191-201.	0.5	12
11	Use of the Indirect Photoluminescence Peak as an Optical Probe of Interface Defectivity in MoS 2. Advanced Materials Interfaces, 2020, 7, 2000413.	3.7	10
12	Relation between film thickness and surface doping of MoS2 based field effect transistors. APL Materials, 2018, 6, .	5.1	9
13	A novel self-aligned double patterning integrated with Ga+ focused ion beam milling for silicon nanowire definition. Microelectronic Engineering, 2021, 237, 111493.	2.4	2
14	Contact Interface Characterization of Graphene contacted MoS2 FETs., 2021, , .		О